

PTO-1449

OCT 15 2004

Application No.

Applicant(s)

**Information Disclosure Citation  
in an Application**

10/696,326

Zhang et al.

Docket Number

Group Art Unit

Filing Date

064441.0266

1756

10/29/2003

## U.S. PATENT DOCUMENTS

|           | DOCUMENT NO. | DATE     | NAME             | CLASS | SUBCLASS | FILING DATE |
|-----------|--------------|----------|------------------|-------|----------|-------------|
| <i>AB</i> | 3927943      | 12/23/75 | Pohl et al.      | 355   | 132      | 07/01/74    |
| B.        | 4032233      | 06/28/77 | Oscarsson et al. | 355   | 91       | 05/03/76    |
| C.        | 4131363      | 12/26/78 | Shea et al.      | 355   | 75       | 12/05/77    |
| D.        | 4159176      | 06/26/79 | de Masi          | 355   | 79       | 11/14/77    |
| E.        | 4255216      | 03/10/81 | Conant et al.    | 156   | 80       | 01/14/80    |
| F.        | 4470508      | 09/11/84 | Yen              | 206   | 334      | 08/19/83    |
| G.        | 4536240      | 08/20/85 | Winn             | 156   | 74       | 02/22/83    |
| H.        | 4584216      | 04/22/86 | Kenworthy et al. | 428   | 38       | 06/15/84    |
| I.        | 4657805      | 04/14/87 | Fukumitsu et al. | 428   | 215      | 06/13/85    |
| J.        | 4737387      | 04/12/88 | Yen              | 428   | 14       | 07/07/86    |
| K.        | 4833051      | 05/23/89 | Imamura          | 430   | 5        | 12/17/87    |
| L.        | 4948851      | 08/14/90 | Squire           | 526   | 247      | 12/28/89    |
| M.        | 4973142      | 11/27/90 | Squire           | 350   | 409      | 04/09/90    |
| N.        | 5008156      | 04/16/91 | Hong             | 428   | 506      | 12/06/98    |
| <i>RC</i> | 5061024      | 10/29/91 | Keys             | 359   | 350      | 09/06/89    |

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|           | DOCUMENT NO. | DATE     | COUNTRY            | CLASS | SUBCLASS | TRANSLATION |    |
|-----------|--------------|----------|--------------------|-------|----------|-------------|----|
|           |              |          |                    |       |          | YES         | NO |
| <i>AP</i> | 2000292909   | 10/20/00 | JP (abstract only) | G03F  | 1/14     | X           |    |
| <i>AQ</i> | 10062966     | 03/06/98 | JP (abstract only) | G03F  | 1/14     | X           |    |

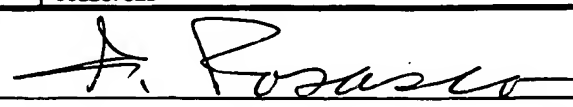
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|           | DOCUMENT (Including Author, Title, Source, and Pertinent Pages)   | DATE               |
|-----------|---|--------------------|
| <i>AR</i> | International PCT Search Report with Notification of Transmittal, PCT/US03/34485, 8 pages.  | Mailed<br>07/29/04 |
| <i>AS</i> | Bernal, M.P. et al., "Natural Zeolites and Sepiolite as Ammonium and Ammonia Adsorbent Materials", Bioresource Technology 43 (1993) pp. 27-33.  | 1993               |
| <i>AT</i> | Bernal, M.P. et al., "Application of Natural Zeolites for the Reduction of Ammonia Emissions during the Composting of Organic Wastes in a Laboratory Composting Simulator", Bioresource Technology 43 (1993) pp. 35-39. | 1993               |
| <i>AU</i> | Grayfer et al., "Protecting 248 nm Lithography from Airborne Molecular Contamination during Semiconductor Fabrication", Proceedings of SPIE Vol. 4346 (2001), pp. 676-694. Optical Microlithography XIV.                | 2001               |

EXAMINER

DATE CONSIDERED

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|   |    |   |          |                    |                 |             |                       |
|---|----|---|----------|--------------------|-----------------|-------------|-----------------------|
| <b>PTO-1449</b><br><br><b>Information Disclosure Citation<br/>in an Application</b>   |    | Application No.   |          | Applicant(s)       |                 |             |                       |
|   |    | 10/696,326  |          | Zhang et al.       |                 |             |                       |
|   |    | Docket Number   |          | Group Art Unit     |                 | Filing Date |                       |
|   |    | 064441.0266   |          | 1756               |                 | 10/29/2003  |                       |
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|   |    | DOCUMENT NO.  | DATE     | NAME               | CLASS           | SUBCLASS    | FILING DATE           |
| <input checked="" type="checkbox"/>   | A. | 5260585   | 11/09/93 | Tom                | 250             | 573         | 06/12/92              |
| <input checked="" type="checkbox"/>   | B. | 5487771   | 01/30/96 | Zeller             | 55              | 523         | 07/27/94              |
| <input checked="" type="checkbox"/>   | C. | 5723860   | 03/03/98 | Hamada et al.      | 250             | 239         | 06/28/96              |
| <input checked="" type="checkbox"/>   | D. | 5856018   | 01/05/99 | Chen et al.        | 428             | 448         | 06/17/96              |
| <input checked="" type="checkbox"/>   | E. | 5928410   | 07/27/99 | Jois et al.        | 95              | 51          | 12/09/97              |
| <input checked="" type="checkbox"/>   | F. | 6083577   | 07/04/00 | Nakagawa et al.    | 428             | 14          | 03/17/98              |
| <input checked="" type="checkbox"/>   | G. | 6149992   | 11/21/00 | Nakayama           | 428             | 14          | 10/19/98              |
| <input checked="" type="checkbox"/>   | H. | 6254942   | 07/03/01 | Tanaka             | 428             | 14          | 06/07/00              |
| <input checked="" type="checkbox"/>   | I. | 6277342   | 08/21/01 | Pearlstein et al.  | 423             | 210         | 08/23/99              |
| <input checked="" type="checkbox"/>   | J. | 6383258   | 05/07/02 | Simmons            | 95              | 45          | 12/19/00              |
| <input checked="" type="checkbox"/>   | K. | 6395066   | 05/28/02 | Tanihara et al.    | 95              | 47          | 02/23/00              |
| <input checked="" type="checkbox"/>   | L. | 6428583   | 08/06/02 | Reuter             | 23              | 301         | 04/27/00              |
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| <input checked="" type="checkbox"/>   | M. | 2001350252  | 12/21/01 | JP (abstract only) | G03F            | 1/14        | X                     |
| <input checked="" type="checkbox"/>   | N. | 04198117  | 07/15/92 | JP (abstract only) | H01L            | 21/027      | X                     |
| <input checked="" type="checkbox"/>   | O. | 10198021  | 07/31/98 | JP (abstract only) | G03F            | 1/14        | X                     |
| <input checked="" type="checkbox"/>   | P. | 01/59522 A1   | 08/16/01 | WO                 | G03F            | 1/14        | X                     |
| <input checked="" type="checkbox"/>   | Q. | 2004/031855 A2  | 04/15/04 | WO                 | G03F            | -           | X                     |
| <input type="checkbox"/>  | R. |   |          |                    |                 |             |                       |
| <input type="checkbox"/>  | S. |   |          |                    |                 |             |                       |
| <b>NON-PATENT DOCUMENTS</b>   |    |   |          |                    |                 |             |                       |
|   |    | DOCUMENT (Including Author, Title, Source, and Pertinent Pages)   |          |                    |                 |             | DATE                  |
| <input checked="" type="checkbox"/>   | T. | Kinhead et al., "Targeting Gaseous Contaminants in Wafer FABS: Fugitive Amines", Microcontamination, pp. 37-40.   |          |                    |                 |             | 06/1993               |
| <input checked="" type="checkbox"/>   | U. | Cullins et al., "157-nm Photomask Handling and Infrastructure: Requirements and Feasibility", Proceedings of SPIE Vol. 4409 (2001), pp. 632-640, Photomask and Next-Generation Lithography Mask Technology VIII; XP-002287329 |          |                    |                 |             | 2001                  |
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|    |    |   |          |                    | <b>5-31-05</b>  |             |                       |
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|                       | DOCUMENT NO. | DATE     | NAME              | CLASS | SUBCLASS | FILING DATE |  |
| A.                    | 6433356      | 08/13/02 | Cahen et al.      | 257   | 40       | 07/14/99    |  |
| B.                    | 6435586      | 08/20/02 | Getzschman et al. | 296   | 37.6     | 04/13/01    |  |
| C.                    | 6436586      | 08/20/02 | Matsuoka et al.   | 430   | 5        | 04/06/00    |  |
| D.                    | 6443302      | 09/03/02 | Tanaka            | 206   | 316.1    | 04/26/01    |  |
| E.                    | 6444608      | 09/03/02 | Oki et al.        | 502   | 300      | 10/17/01    |  |
| F.                    |              |          |                   |       |          |             |  |
| G.                    |              |          |                   |       |          |             |  |
| H.                    |              |          |                   |       |          |             |  |
| I.                    |              |          |                   |       |          |             |  |
| J.                    |              |          |                   |       |          |             |  |
| K.                    |              |          |                   |       |          |             |  |
| L.                    |              |          |                   |       |          |             |  |

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|                          |              |      |         |       |          | YES         | NO |
| M.                       |              |      |         |       |          |             |    |
| N.                       |              |      |         |       |          |             |    |
| O.                       |              |      |         |       |          |             |    |

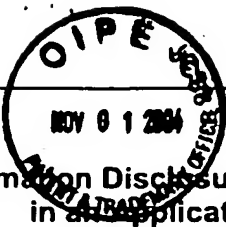
  

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| T.                   |   |      |
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| EXAMINER <i>A. Tosasco</i> | DATE CONSIDERED<br><i>5-31-05</i> |
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| D. |              |      |      |       |          |             |
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|-------|---|-----------|
| DR R. | Kishkovich, Oleg, et al., "Airborne Molecular Contamination Control for DUV Lithography", Cleanroom Technology, vol. 6(5), pp. 31-33. | June 2000 |
| S.    |   |           |
| T.    |   |           |
| U.    |   |           |

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